



05-27-03

MEMC 985401 (23401)
PATENT

1705

#7
5/29/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Vladimir V. Voronkov et al.

Art Unit 1765

Serial No. 09/972,608

Filed October 5, 2001

Confirmation No. 4591

For METHOD FOR THE PRODUCTION OF LOW DEFECT DENSITY SILICON

Examiner Matthew J. Song

RECEIVED
MAY 28 2003
TC 1700

May 23, 2003

RESPONSE TO RESTRICTION REQUIREMENT

TO THE COMMISSIONER FOR PATENTS

P.O. Box 1450

Alexandria, VA 22313-1450

SIR:

In response to the restriction requirement dated April 25, 2003, Applicants elect examination of claims 37-43 (Group II).

Applicants therefore withdraw from consideration, without prejudice to their patentability, claims 1-36 (Group I) and claims 44-45 (Group III). Applicants also expressly reserve the right to file one or more divisional applications directed to these claims in the future.

Respectfully submitted,

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